

17 July 2003 SciFinder Page

Answer 1:

Riblingraphic Information

Positive-type photoresist composition with low toxicity. Yoshimoto, Hiroshi; Suzuki, Nobuo. (Fuji Photo Film Co., Ltd., Japan). J Kokai Tokkyo Koho (1997), 13 pp. CODEN: JKXXAF JP 09244231 A2 19970919 Heisei. Patent written in Japanese.

Application: IP 96-52008 19960308 CAN 127:301274 AN 1997:619206 CAPLUS (Copyright 2003 ACS)

Patent Family Information

| Patent No | Kind | Date . | Application No | Date |
|----------------------|------|----------|----------------|----------|
| IP 09244231 | A2 | 19970919 | IP 1996-52008 | 19960308 |
| | | | | |
| Priority Application | | | | |
| IP 1996-52008 | | 19960308 | | |

Abstract

The compn. has (A) an alk.-sol. resin, (B) 1,2-naphthoquinonediazide-4-sulfonate and/or 1,2-naphthoquinonediazide-5-sulfonate, and (C alkoxybutylacetate and/or alkoxypentylacetate. The compn. is useful for manufg. a semiconductor device, a liq. crystal, a printed circuit hoard etc. The compn. shows low toxicity storage stability good application property high resoln. low striation, and heat resistance

Patent Classifications

Main IPC: G03F007-004 Secondary IPC: G03F007-022: H01L021-027

Indexing - Section 74-5 (Radiation Chemistry Photochemistry and Photographic and Other Reprographic Processes)

Phenolic resins uses

Role: DEV (Device component use): USES (Uses)

(novolak) nos -type photoresist compa conto alkoxybutylacetate and/or alkoxypentylacetate with low toxicity)

Photoresists

(nos -type: nos -type photoresist compn. conto. alkoxybutylacetate and/or alkoxybentylacetate with low toxicity)

68510-93-0

107761-81-9 2 3 4 4'-Tetrahvdroxvhenzonhenone 1 2-nanhthoquinonediazide-5-sulfonate 136830-28-9

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$$N_2$$
 N_2

143213-15-4

168634-43-3

197220-63-6

197220-66-9

Role: DEV (Device component use); USES (Uses)

(pos.-type photoresist compn. contg. alkoxybutylacetate and/or alkoxypentylacetate with low toxicity)

27029-76-1P, m-Cresol-p-cresol-formaldehyde copolymer

Role: DEV (Device component use); IMF (Industrial manufacture); PREP (Preparation); USES (Uses) (pos.-type photoresist compn. contg. alkoxybutylacetate and/or alkoxypentylacetate with low toxicity)

4435-53-4, 3-Methoxybutylacetate

103429-90-9, 3-Methoxy-3-methylbutylacetate

Role: DEV (Device component use); MOA (Modifier or additive use); USES (Uses)

(pos.-type photoresist compn. contg. alkoxybutylacetate and/or alkoxypentylacetate with low toxicity)

Supplementary Terms

photoresist pos type alkoxybutylacetate alkoxypentylacetate; naphthoquinonediazide sulfonate toxicity free photoresist